

Dr. Matthias Vaupel is physicist. He received a Ph.D. from the university of Hannover (Germany) for investigations of nonlinear optical effects in lasers. After 2 years of post-doctoral research at Lab. Kastler-Brossel, Université Paris 6, he joined Nanofilm Technologie GmbH (now Accurion) in Göttingen (Germany) where he developed an integrated imaging ellipsometer with scanning probe microscope (SPEM). In 2008 he moved to Carl Zeiss Microscopy GmbH as application specialist of material inspection with light microscopy. His major expertise is in confocal and interference contrast microscopy.